| Session Title: | [TuG1] Frontier Metrology and Modeling I |
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| Session Date: | November 12 (Tue.), 2024 |
| Session Time: | 13:00-14:25 |
| Session Room: | Room G (Meeting Room, 5F, Grand Josun Busan) |
| Session Chair: | Prof. Hyungtak Seo (Ajou Univ., Korea) |

| [TuG1-1] [Plenary] | 13:00-13:45 |
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Process Optimization and Control in Dry Etch

Ye Feng (Intel, USA)

| [TuG1-2] | 13:45-14:05 |
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Etch Rate Uniformity Monitoring for Photoresist Etch Using Multi-Channel Optical Emission Spectroscopy in an Inductively Coupled Plasma Reactor

Sang Hee Han, Sanghoon Lee, Jaehyeon Kim, Eunchong Park, and Heeyeop Chae (Sungkyunkwan Univ., Korea)

| [TuG1-3] | 14:05-14:25 |
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Measuring Electrical Resistivity of p-Type Si Wafer with Low Dopant Concentration and Its Dependence on Thermal Donor Formation and Surface Treatments

Seob Shim, Gyuhyeok Choi, Mingyu Park, and Woosung Lee (SK Siltron, Korea)